THE UNITED STATES PATENT AND TRADEMARK OFFICE

REVOCATION AND NEW POWER OF ATTORNEY AND CHANGE OF CORRESPONDENCE ADDRESS

I, Dr. Graham Fisher, Director of Intellectual Property of MEMC Electronic Materials, Inc., the Assignee of the entire right, title, and interest in the U.S. Patent Application(s) and/or Patent(s) identified on the attached Schedule A, hereby revoke all previous powers of attorney or authorizations of agent given and do hereby appoint the attorneys or agents associated with the following Customer Number, with full power of substitution and revocation, to prosecute and transact all business in the Patent and Trademark Office connected therewith for the U.S. Patent Application(s) and/or Patent(s) listed in the attached Schedule A:

Customer Number: 76681

Please direct all correspondence in connection with said U.S. Patent Application(s) and/or Patent(s) to:

Customer Number: 76681

5/13/2008

Respectfully submitted,

Dr. Graham Fisher

Director of Intellectual Property MEMC Electronic Materials, Inc.

THE UNITED STATES PATENT AND TRADEMARK OFFICE

STATEMENT UNDER 37 CFR 3.73(b)

MEMC Electronic Materials, Inc., a Delaware Corporation, pursuant to 37 CFR 3.73(b), hereby states that it is the Assignee of the entire right, title, and interest in U.S. Patent Application(s) and/or Patent(s) on the attached Schedule A.

The entire rights, title, and interest in the aforementioned Patent Application(s) and/or Patent(s) were conveyed to *MEMC Electronic Materials, Inc.* via Assignment(s) recorded with the United States Patent and Trademark Office at the *Reel/Frame Numbers on the attached Schedule A.*

The undersigned, Dr. Graham Fisher, Director of Intellectual Property, has full authorization to act on behalf of Assignee MEMC Electronic Materials, Inc.

Date: 5/13/2008

Respectfully submitted,

Dr. Graham Fisher

Director of Intellectual Property MEMC Electronic Materials, Inc.

APPENDIX A Owned by MEMC Electronic Materials, Inc.

LΕ	STANTIALLY FREE OF FAULTS	STANTIALLY FREE OF FAULTS	SINGLE CRYSTAL SILICON	HAVING A VACANCY- LLY FREE OF OXIDATION	HAVING A VACANCY. LLY FREE OF OXIDATION	T HAVING A HIGH ARSENIC	CON ON INSULATOR GETTERING BY ION	TURE HAVING AN EPITAXIAL	HING HEAD AND METHOD	WAFERS WITH STABILIZED TION CENTERS	ZED OXYGEN PRECIPITATE OCESS FOR MAKING THE	SLE CRYSTAL SILICON USINI ROL TEMPERATURE	CRYSTAL PULLER	ENUDED ZONE DEPTH IN AN SILICON WAFER	3 FOR GROWING A	
ППСЕ	NITROGEN-DOPED SILICON SUBSTANTIALLY FREE OF OXIDATION INDUCED STACKING FAULTS	NITROGEN-DOPED SILICON SUBSTANTIALLY FREE OF OXIDATION INDUCED STACKING FAULTS	SEED CRYSTALS FOR PULLING SINGLE CRYSTAL SILICON	LOW DEFECT DENSITY SILICON HAVING A VACANCY- DOMINATED CORE SUBSTANTIALLY FREE OF OXIDATION INDUCED STACKING FAULTS	Division of 10/054-629 LOW DEFECT DENSITY SILICON HAVING A VACANCY-recorded at DOMINATED CORE SUBSTANTIALLY FREE OF OXIDATION 012789/0747 INDUCED STACKING FAULTS	SINGLE CRYSTAL SILICON INGOT HAVING A HIGH ARSENIC CONCENTRATION	PROCESS FOR PRODUCING SILICON ON INSULATOR STRUCTURE HAVING INTRINSIC GETTERING BY ION IMPLANTATION	SILICON ON INSULATOR STRUCTURE HAVING AN EPITAXIAL LAYER AND INTRINSIC GETTERING	POLISHING APPARATUS, POLISHING HEAD AND METHOD	PROCESS FOR MAKING SILICON WAFERS WITH STABILIZED OXYGEN PRECIPITATE NUCLEATION CENTERS	SILICON WAFERS WITH STABILIZED OXYGEN PRECIPITATE NUCLEATION CENTERS AND PROCESS FOR MAKING THE SAME	PROCESS FOR PREPARING SINGLE CRYSTAL SLICON USING CRUCIBLE ROTATION TO CONTROL TEMPERATURE GRADIENT	FLUID SEALING SYSTEM FOR A CRYSTAL PULLER	PROCESS FOR CONTROLLING DENUDED ZONE DEPTH IN AN IDEAL OXYGEN PRECIPITATING SILICON WAFER	CRYSTAL PULLER AND METHOD FOR GROWING A MONOCRYSTALLINE INGOT	
REEL AND FRAME NO.	Division of 10/380,806 recorded at 014339/0812	014339/0812 N	013562/0482 s	L 012789/0747 D II	Division of 10/054-629 L recorded at 012789/0747	013576/0951 S	Division of 10/177,444 Precorded at 013181/0822 III	013181/0822 S	012328/0298 P	Division of 10/963,340 precorded at 013923/0124	S 013923/0124 N S	2004/0118333 C	013911/0117 F	2003/0192469 F	2004/0112277 C	
CURRENT OWNER/ ASSIGNEE	MEMC Electronic Materials, Inc.	MEMC Electronic Materials, Inc.	MEMC Electronic Materials, Inc	MEMC Electronic Materials, Inc.	MEMC Electronic Materials, Inc.	MEMC Electronic Materials, Inc.	MEMC Electronic Materials: Inc.	MEMC Electronic Materials Inc	MEMC Electronic Materials, Inc.	MEMC Electronic Materials, Inc	MEMC Electronic Materials Inc	MEMC Electronic Materials, Inc	MEMC Electronic Materials, Inc.	MEMC Electronic Materials Inc	MEMC Electronic Materials, Inc.	
PATENT NO. ISSUE DATE		7,182,809 2/27/2007	6,866,713 3/15/2005	6,846,539 1/25/2005	7.217.320 5/15/2007	7,132,091	7.071,080 7/4/2006	6,930,375 8/16/2005	6,712,673 3/30/2004	7,201,800 4/10/2007	6,808,781 10/26/2004	7,125,450 10/24/2006	6,942,733 9/13/2005			
SERIAL NO. FILING DATE	11/623,142 1/15/2007		10/281,632 10/28/2002	10/054,629 1/22/2002	11/005,987	10/256,759 9/27/2002	11/174.908 7/5/2005	10/177,444 8/21/2002	********	10/963,340 10/12/2004	10/328,481 12/23/2002	10/899,038 10/31/2003	10/465,528 6/19/2003	10/277,660 10/22/2002		2 0 0 0
PUBLICATION NO. & DATE	US2007-0169683-A1 7/26/2007	US-2004-0009111-A1 1/15/2004	US-2003-0079673-A1 5/1/2003	US-2002-0100410-A1 10/054,629 8/1/2002 1/22/2002	US-2005-0150445 A1 7/14/2005	US-2003-0061985-A1 4/3/2003	US-2005-0255671-A1 11/17/2005	US-2003-0008435-A1 1/9/2003	US-2003-0068958-A1 4/10/2003	US: 2005-0048247-A1 3/3/2005	US-2003-0136961-A1 10/328,481 7/24/2003	US-2004-0118333-A1 6/24/2004	US2004-0255847 A1 12/23/2004	US-2003-0192469-A1 10/16/2003	US-2004-0112277.A1 6/17/2004	
CONF. NO	4312	1990	3830	5778	5113	4314	3201	5976	2873	2878	8328	1197	2404	6422	5409	
ATTORNEY REFERENCE	28744-215 (MEMC2905 16)	MEMC2905.9	MEMC2907.1	MEMC2960.1	MEMC2960.9	MEMC2970.1	MEMC2984.10	MEMC2984.2	MEMC2992	MEMC3004 10	MEMC3004.2	MEMC3005.3	MEMC3007	28744-107 (MEMC3011.1)	28744-138 (MEMC3035.1)	